

Third Party Resist Supplier Evaluation of TriFact Solutions, Inc. DI Water Heater Model TFS 4000-TP Pattern Area Defects



Project Objective

 Study the effect of a heated deionized (DI) water rinse on the formation of post develop pattern defects.



Equipment

- TEL Mark 8 coat/develop tool
- TriFact Solutions DI water Heater Model TFS 2000-TP
- Tridak Low Volume Dispense Assembly
- ASML PAS5500/850 stepper
- K-T8100 Top Down CD SEM
- K-T2135 Defect Inspection tool
 - Narrowband illumination with a Hg-Xenon light source and filtered wavelength.
 - Inspection wavelength around 580nm.



KLA-Tencor2135 Defect Inspection Parameters

KLA2135 Defect Inspection tool

- Pixel setting: $\underline{\mathbf{0.25}} \, \mu \mathrm{m}$

Inspection Mode: Array

- Threshold: 20

- Filter set: f2

- Inspected area: <u>69.07</u> sq./cm. Patterned Resist

Area <u>35.85</u> sq./cm. Unexposed Resist

Area 35.06 sq./cm. Bulk Exposed

Resist Area



Results Summary Table Pattern Area Defects

	Standard			Heated	
	Rinse Temperature			Rinse Temperature	
DI Water		Defect			Defect
Rinse Time	Defect Count	Density (defects/sq. cm.)		Defect Count	Density (defects/sq. cm.)
20 sec.	166	2.40		112	1.62
20 sec.	237	3.43		117	1.69
20 sec.					
40 sec.	251	3.63		118	1.71
40 sec.	269	3.89		116	1.68
40 sec.				224	3.24
60 sec.	133	1.93		138	2.00
60 sec.	120	1.74		144	2.08
60 sec.	156	2.26		74	1.07
80 sec.	179	2.59		79	1.14
80 sec.	204	2.95		73	1.06
80 sec.				68	0.98

The heater setting is at 40°C but the actual temperature at the DI water rinse nozzle is 36°C. This is due to the length of exposed tubing between the heater assembly and the dispense tip. For this evaluation, the heater was not able to be configured closer to the DI water dispense nozzle.



JMP Analysis Results of Defect Density's Pattern Area Defects

Standard DI Water Rinse Temp. (21°C) **Oneway Analysis of Defect Density By Rinse Time** 4.5 Density Defect 2.5 1.5 1 Each Pair 40 sec. 60 sec. 80 sec. 20 sec. Student's t 0.05 Rinse Time Means and Std Deviations Std Dev Std Err Mean Lower 95% Level Number Mean Upper 95% 2.91500 0.728320 20 sec. 0.51500 -3.6299.4587 40 sec. 3.76000 0.183848 0.13000 2.108 5.4118 60 sec. 1.97667 0.263122 0.15191 1.323 2.6303 80 sec. 2.77000 0.254558 0.18000 0.483 5.0571

Heated DI Water Rinse Temp. (40°C) Oneway Analysis of Defect Density. By Rinse Time 4.5 4 Density 2 Defekt 2 1.5 0.5 Each Pair 20 sec. 40 sec. 60 sec. 80 sec. Student's t 0.05 Rinse Time Means and Std Deviations Level Number Mean Std Dev Std Err Mean Lower 95% Upper 95% 20 sec. 1.65500 0.049497 0.03500 1.210 2.0997 40 sec. 2.21000 0.892132 0.51507 -0.006 4.4262 0.322 60 sec. 1.71667 0.561456 0.32416 3.1114

1.06000 0.080000

0.04619

0.861

1.2587

With a standard rinse temperature, a 60sec. rinse time significantly reduces post develop defects.

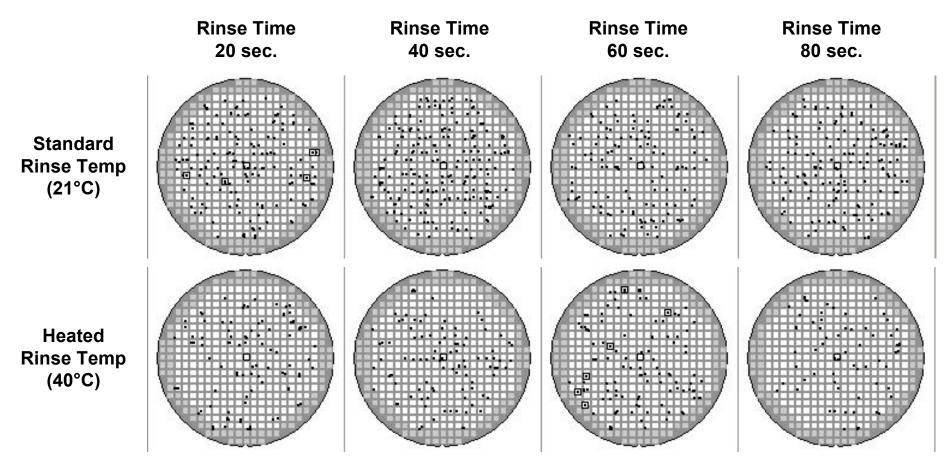
A heated DI water rinse produced lower counts at a shorter rinse and continues to maintain or reduce that count with extended rinse time. An 80 sec rinse was on significantly different than the 40 sec rinse.

Note: 40°C is the set point temperatures on the heating assembly. Actual temperature at the Nozzle is 36°C.

80 sec.



Wafer Maps Pattern Area Defects





Classification Codes Pattern Area Defects

- Sm Dark Small dark point defects (<0.25μm in size).
- Sm Bright Small light point> defects (<0.25μm in size).
- Rnd/Med Dark Round and darker than the background.
- Irr Dark Irregular shape and darker than the background.
- Irr Bright Irregular shape and brighter than the background.
- Macro Greater than 10μm in size.



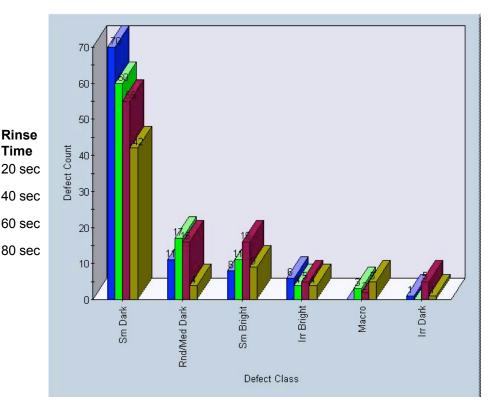
Pareto Charts Pattern Area Defects

One wafer classified per process condition. Up to 100 defects classified per wafer.

Standard Rinse Temperature (21°C)

Sm Bright In Bri

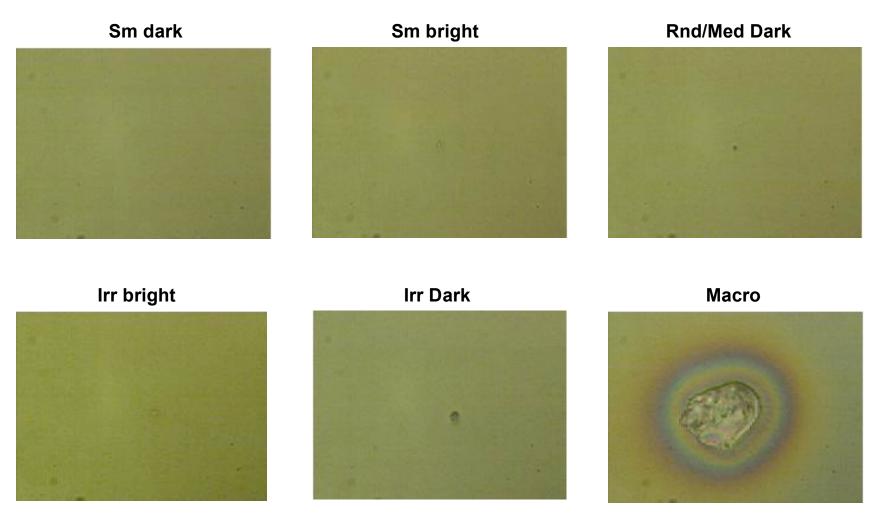
Heated Rinse Temperature (40°C)



TriFact Solution Confidential



Optical Images of Defect Types Pattern Area Defects



TriFact Solution Confidential



Results Summary Pattern Area Defects

- Analysis of the defect density's show:
 - With a standard rinse temperature, a 60sec. rinse time significantly reduces post develop defects.
 - A heated DI water rinse produced lower counts at a shorter rinse and continues to maintain or reduce that count with extended rinse time. An 80 sec rinse was on significantly different than the 40 sec rinse.
- Review of defects show:
 - Using a standard rinse temperature, increasing the rinse time saw in increase in Sm Dark and a reduction in Rnd/Med dark defects.
 - A heated DI water rinse reduced Sm Dark.